2025년 2월 12일(수)-14일(금) | 강원도 하이원리조트

Future Normal in Semiconductor

2025년 2월 13일(목), 09:00-10:45 Room B(그랜드볼룸III), 4층

K. Memory (Design & Process Technology) 분과 O02_[TB1-K] Charge Trapped Memory Application - I

좌장: 강대웅 교수(서울대학교), 전종욱 교수(성균관대학교)

	ゴロ・ロロら エテ(ハヹロキエ), じらず エテ(ロビごロキエ) ,	
초청 TB1-K-1	Key Challenges of VNAND Unit Cell Design for Higher Layer Stacking	
	Doo Hee Hwang, Sang Hoon Kim, Seung Jae Baik, and Jae duk Lee	
09:00-09:30	Flash TD Team, Semiconductor R&D Center, Samsung Electronics Co., Ltd.	
	Array-level NAND Cell Simulator for Feasibility Assessment of Novel	
TB1-K-2	Memory Cells in 3D NAND Architecture	
09:30-09:45	Seong Hwan Kong and Wonbo Shim	
	Seoul National University of Science and Technology	
	Improved Memory Characteristics of MONOS Device with High-k dots	
TB1-K-3 09:45-10:00	Embedded Si₃N₄ Charge Trap Layer	
	Seongho Lee ¹ , San Park ¹ , Sehyeon Choi ¹ , Yun Seo Lim ¹ , Hyungjun Kim ² , Jaehyun	
	Yang ² , Bio Kim ² , Youngseon Son ² , Hanmei Choi ² , and Changhwan Choi ¹	
	¹ Division of Materials Science & Engineering, Hanyang University, ² Memory Process	
	Development Team, Samsung Electronics Co., Ltd.	
	Analysis of the Dominant Mechanism in Hybrid NAND Flash for Enhanced	
	Memory Window	
TB1-K-4	Jaeseon Eo ¹ , Kihoon Nam ¹ , Donghyun Kim ¹ , Jiyoon Kim ¹ , Sanghun Jeon ² , and Rock-	
	Hyun Baek ¹	
10:00-10:15	¹ Department of Electrical Engineering, POSTECH, ² School of Electrical Engineering,	
	KAIST	
	Leveraging Negative Capacitance for Reducing Operating Voltage in High-	
	Density 3D NAND Technology	
TB1-K-5	Sangho Lee, Yunseok Nam, Giuk Kim, Hunbeom Shin, Seokjoong Shin, and Sanghun	
10:15-10:30	Jeon	
	School of Electrical Engineering, KAIST	

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	Unveiling the Origin of Disturbance in FeFET and the Potential of
TB1-K-6	Multifunctional TiO ₂ as a Breakthrough for Disturb-free 3D NAND Cell
10:30-10:45	Hyunjun Kang, Giuk Kim, and Sanghun Jeon
	School of Electrical Engineering, KAIST